



**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q81014

Shuho MOTOMURA

Appln. No.: 10/820,791

Group Art Unit: Not Yet Assigned

Confirmation No.: Not Yet Assigned

Examiner: Not Yet Assigned

Filed: April 9, 2004

For: A RESIST FILM FORMING METHOD AND A PHOTOMASK MANUFACTURING METHOD

**SUBMISSION OF DRAWINGS**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Submitted herewith please find 7 sheets (Figures 1-8) of drawings in compliance with 37 C.F.R. § 1.84. The Examiner is respectfully requested to acknowledge receipt of these drawings.

Respectfully submitted,

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CUSTOMER NUMBER

Date: May 28, 2004